



Contribution ID: 488

Type: **Poster Presentation**

AFM and SEM studies on iodine implanted 6H-SiC

Thursday, 12 July 2012 17:30 (2 hours)

Abstract content
 (Max 300 words)

The study of ion beam modification of surfaces has increasingly become an integral part of characterising silicon carbide and related nuclear materials. The effect of a relatively high fluence (2×10^{17} ions) of iodine on the surface of 6H-SiC has been investigated. The contribution of vacuum annealing to the evolution of the surface morphology was also studied. Isochronal vacuum annealing was performed at temperatures ranging from 350 °C to 1200 °C. Atomic force microscopy (AFM) and high resolution scanning electron microscopy (FEG SEM) were employed to analyse the surface microstructure.

Apply to be considered for a student award (Yes / No)?

Yes

Level for award (Hons, MSc, PhD)?

PhD

Main supervisor (name and email) and his / her institution

Prof JB Malherbe
johan.malherbe@up.ac.za
University of Pretoria

Would you like to submit a short paper for the Conference Proceedings (Yes / No)?

No

Primary author: Mr KUHUDZAI, Remeredzai Joseph (University of Pretoria)

Presenter: Mr KUHUDZAI, Remeredzai Joseph (University of Pretoria)

Session Classification: Poster Session

Track Classification: Track A - Division for Condensed Matter Physics and Materials